



PATENT
2557-000177/US

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANTS: Chang Won CHOI et al. CONF. NO.: 5346
SERIAL NO.: 10/762,526 GROUP: 1792
FILED: January 23, 2004 EXAMINER: Lund, Jeffrie R.
FOR: WAFER EDGE ETCHING APPARATUS AND METHOD

AMENDMENT

Customer Service Window
Randolph Building
401 Dulany Street
Alexandria, VA 22314
Mail Stop Amendment

May 16, 2008

Dear Sir:

Responsive to the Official Action dated November 16, 2007, the due date having been extended three (3) months to May 16, 2008, the following amendments and remarks are respectfully submitted in connection with the above-referenced application.

Amendments to the claims begin on page 2 of this paper.

Remarks begin on page 11 of this paper.

	Claims remaining after Amendment		Highest number previously paid for		Present extra
Total	44	-	44	=	0
Independent	6	-	6	=	0

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